

REMARKS

As stated in the Response mailed April 2, 2003, the Examiner rejected claim 62 under 35 U.S.C. §102(b) as being anticipated by US Pat. 5,479,252 to Worster et al. Applicant respectfully disagrees with this rejection if applied again to the above claims.

As stated by the Examiner, in U.S. Patent 5,479,252, Worster et al. disclose a system for inspection and analysis of a semiconductor wafer. The system includes a light source (201); a X-Y scanner (207); a turret (223) supporting a plurality of objective lenses (205) wherein a particular objective lens is able to select to insert into the optical path of the system; a stage (224) movable in three directions via a mechanism (216 – 218); a detection system (212) for detecting light from the wafer; a data processing system (213) for collecting and analyzing the data received by the detection system.

However, the amended claim 62 is directed to a wide field of view scanner for delivering excitation light and detecting excited fluorescent light. The scanner includes a scanning assembly for **displacing an objective lens in a scanning motion**, while the optical path provided by the displaced objective lens and the scanning assembly has a substantially constant length.

There are fundamental differences between the present invention (claimed in independent claims 62, 72, and 82) and the teaching of Worster. Worster does not disclose a scanner for delivering excitation light and detecting the excited fluorescent light. Worster does not disclose a scanner with a scanning assembly for displacing an objective lens in a scanning motion. Actually, Worster teaches a stationary objective lens during scanning after the appropriate lens was selected from several lenses mounted on a turret. That is, during the scanning process, in the Worster system, the final lens is stationary and the irradiated substrate is displaced using a moving stage.

Accordingly, all pending claims 62 through 89 are in condition for allowance and such action is respectfully requested.

There should be no fee associated with this response, but in any case please

charge all US PTO fees, and apply all credits to the Deposit Account No.
01-0431.

Respectfully submitted,

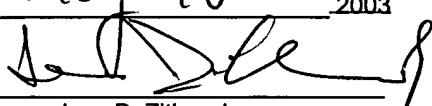


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The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

May 16, 2003

Ivan D. Zitkovsky